

<b>Notice of References Cited</b>	Application/Control No. 10/552,728	Applicant(s)/Patent Under Reexamination FUJINO ET AL.	
	Examiner PAUL A. WARTALOWICZ	Art Unit 1793	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kreiskott, "Continuous electropolishing of Hastelloy substrates for ion beam assisted deposition of MgO. Superconductor science and technology, 16, 613-616, 2003
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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